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PATENT APPLICATION

RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 1753

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Satoshi TATSUURA et al.

Group Art Unit: 1753

Application No.: 10/082,228

Examiner: E. Wong

Filed: February 26, 2002

Docket No.: 106200.01

For: METHOD FOR ELECTRODEPOSITED FILM FORMATION, METHOD FOR  
ELECTRODE FORMATION, AND APPARATUS FOR ELECTRODEPOSITED FILM  
FORMATION

AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the July 14, 2004, Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**

Do not enter. 65 11/13/04